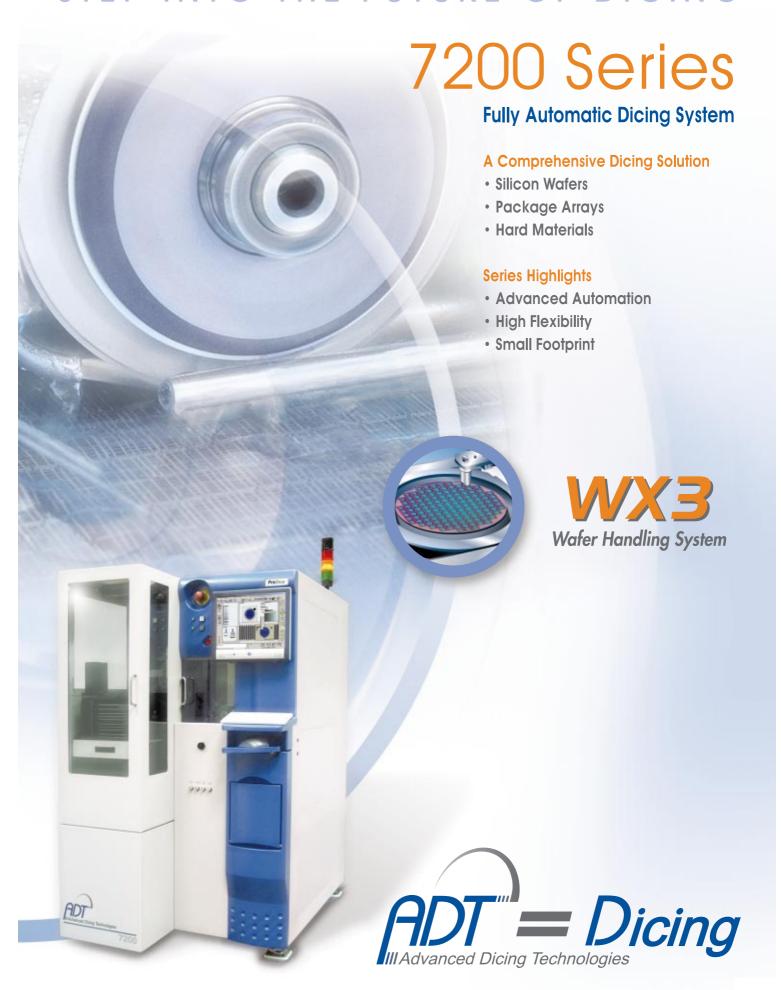
STEP INTO THE FUTURE OF DICING





Simultaneous wafer processing via three coordinated wafer stations to avoid bottleneck slowdown

- Finger extracts wafer from cassette, loading arm (Dicer) loads wafer to dicing chuck → Dicing
- Wet arm moves wafer from dicer to cleaner → Cleaning
- Unloading arm (Cleaner) returns wafer back to cassette (through transfer tray)



- Reduces cost
 - Increases UPH

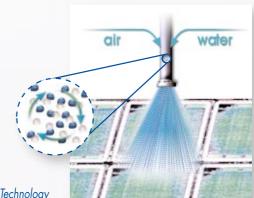
STEP INTO THE

7200 Series

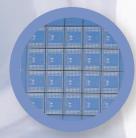
Fully Automatic Dicing System

Semiconductor manufacturers face new production challenges as they struggle to improve dicing quality and throughput while minimizing cost. At ADT we strive to be fully tuned in to our customers' requirements. Hence, our new 7200 fully automatic system comes with innovative and exciting features that set new industry standards for automation, productivity, ease-of-use and affordability.

The 7200 system offers a wide range of advanced automation and process monitoring options to meet the throughput & quality requirements of your most challenging dicing applications: Silicon, Glass on Silicon and GaAs wafers, BGA & QFN packages, LTCC, PCB and other hard material applications.



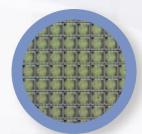
Atomized Cleaning Technology



LTCC Substrate



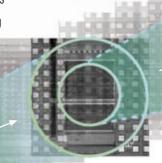
BGA Substrate

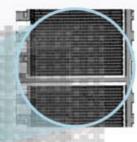


Silicon Wafer

Features & Benefits

- Unique WX3 Wafer Handling System streamlines wafer flow for greater productivity
- Continuous Digital Magnification Vision System provides fast and accurate alignment of wafers for maximum throughput
- Special Algorithm predicts blade wear rates to reduce height measurement time and increase UPH
- Touch Panel Display supports a user-friendly graphical interface (GUI)
- Atomized Wafer Cleaning Technology for superior process results
- Dedicated Dressing Cassette enables automatic blade dressing
- Built-in Inspection Tray allows in-process quality assessment
- · Small footprint





Continuous Digital Magnification Vision System, provides optimal magnification for any eye-point, from X1 (8 micron/pixel) to X8 (1 micron/pixel)

FUTURE OF DICI

7200 Models



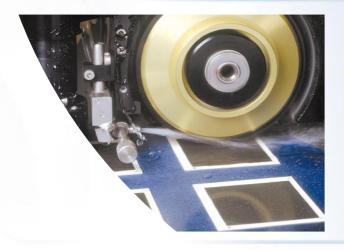
ProDice

2"-3", DC-brushless, Air-bearing, 1.2KW, 60 Krpm Spindle, optimized for IC applications.



MegaDice

2"-3" High-torque, DC-brushless, Air-bearing, 2.4KW, 60 Krpm Spindle, optimized for package singulation and IC applications.

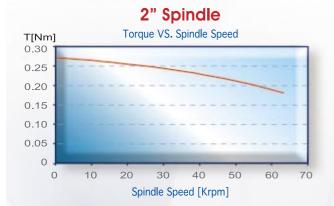


GigaDice

4"-5" High-torque, DC-brushless, Air-bearing, 2.5KW, 30 Krpm Spindle, optimized for automated dicing of hard materials.

7200 Series

High Flexibility





Spindle Speed [Krpm]





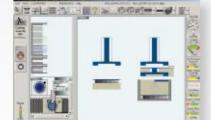
- Front-mounted spindle reduces vibrations and thermal expansion effects
- DC-brushless, direct drive motor provides closed-loop speed control
- Compatible with 2"-3" hub and annular blades
- Flat torque curve guarantees consistent results

User-Friendly Interface



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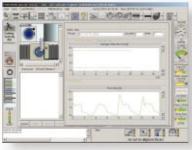
Vision Screen



MI DI DI CI

Main Screen (Automation View)

Main Screen (General View)



Load Monitor

7200 Series

Specifications

	ProDice	MegaDice	GigaDice
Work piece Size	Ø 200 mm	Ø 200 mm	Ø 200 mm
work piece size	Ø 200 HIII		Ø 200 mm
		Package singulation –	
	0.11	up to 235 X 170 mm	111 - 111
Blade Size		- 3"	4" - 5"
Spindle	1.2 KW, Air bearing DC-	2.4 KW, Air bearing DC-	2.5 KW, Air bearing DC-
	brushless 60 Krpm	brushless 60 Krpm	brushless 30 Krpm
Indexing Axis (Y)			
Drive	Ball Bearing Lead Screw with stepper motor		
Control	Linear encoder		
Resolution	0.2 μ m		
Cumulative accuracy	1.5 µm		
Indexing accuracy	1.0 µm		
Feed Axis (X)		1.0 μπ	
Drive	Dall Doo	ring load Caraw with DC brushla	on motor
	Ball Bearing lead Screw with DC-brushless motor		
Feed rate		Up to 700 mm/sec	
Cut Depth Axis (Z)			
Drive	Ball Bearing lead Screw with stepper motor		
Resolution	0.2 μm		
Accuracy	$2.0~\mu{ m m}$		
Repeatability	1.0 μm		
Rotary Axis (T)		p	
Drive	Clo	ose Loop, Direct Drive, DC-brush	less
Accuracy	4 arc-sec (0.001 deg.)		
,			
Repeatability	4 arc-sec (0.001 deg.) 350°		
Stroke	Digital Camera		
Vision system	Digital Camera		
	High Bright LED Illumination (Vertical & Oblique)		
	Continuous Magnifi	ication From X1 (8 micron/pixel)	to X8 (1 micron/pixel)
Cleaning Station	Full rinse and dry cycle		
Spinning Speed	100-2500 RPM		
High Pressure	Up to 10 MPa		
	Atomizing capabilities		
	Additives (optional)		
Wafer Handling system	Slot to slot integrity		
	Dress Cassette		
	Inspection Drawer		
	UV curing station (optional)		
	Barcode reader (optional)		
	SECS-GEM host Communication (optional)		
Heer Interfere	Flat 15" touch screen		
User Interface			
	Graphical User Interface (GUI)		
	Multilanguage support		
	Keyboard & Mouse (optional)		
Utilities*			
Electrical	200-240 Single Phase VAC 50/60 Hz		
Air / N2	700 L/min @ 5.5 bar		
	500 L/min compressed air, 200 L/min process air/ N2		
Spindle coolant	1.1 L/min tap water		
Process Water (DI)	Blade/process coolant - Up to 7 L/min		
` '	High Pressure cleaning – Up to 5 L/min		
t nonding model 0, seedlesties			
* pending model & application Dimensions (WxDxH)	піў	965 x 1460 x 1700 mm	min

Specifications may be changed without notice.



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